Abstracts

Near-field scanning microwave microscopy: measuring local microwave properties and electric field distributions

B.J. Feenstra, C.P. Vlahacos, A.S. Thanawalla, D.E. Steinhauer, S.K. Dutta, F.C. Wellstood and S.M. Anlage. "Near-field scanning microwave microscopy: measuring local microwave properties and electric field distributions." 1998 MTT-S International Microwave Symposium Digest 98.2 (1998 Vol. II [MWSYM]): 965-968.

We describe the near-field scanning microwave microscopy of microwave devices on a length scale much smaller than the wavelength used for imaging. Our microscope can be operated in two possible configurations, allowing a quantitative study of either material properties or local electric fields.

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